

| <b>FORM PTO-1449 (Modified)</b><br><b>LIST OF PATENTS AND PUBLICATIONS FOR APPLICANT'S INFORMATION DISCLOSURE STATEMENT (Use several sheets if necessary)</b> |   |           | <b>Attorney Docket No.:</b> 18419-008210US<br><b>Applicant:</b> Sien G. Kang et al.<br><b>Filing Date:</b> Herewith |                 | <b>Application No.:</b><br><b>Group:</b> Unassigned |                              |
|---|---|-----------|---|-----------------|---|------------------------------|
| <b>Reference Designation</b>  |   |           | <b>U.S. PATENT DOCUMENTS</b>  |                 |   | <b>Page 1</b>                |
| Examiner Initial  | Document No.  | Date      | Name  | Class           | Sub-class   | Filing Date (If Appropriate) |
| SL  | AA  | 3,964,957 | 6/22/76   | Walsh           | 156   | 345                          |
|   | AB  | 4,495,219 | 01/22/85  | Kato et al.     | 427   | 82                           |
|   | AC  | 4,906,594 | 03/06/90  | Yoneda et al.   | 437   | 228                          |
|   | AD  | 5,198,071 | 03/30/93  | Scudder et al.  | 156   | 625                          |
|   | AE  | 5,198,371 | 03/30/93  | Li              | 437   | 11                           |
|   | AF  | 5,213,986 | 05/25/93  | Pinker et al.   | 437   | 20                           |
|   | AG  | 5,374,564 | 12/20/94  | Bruel           | 437   | 24                           |
|   | AH  | 5,686,980 | 11/11/97  | Hirayama et al. | 349   | 110                          |
|   | AI  | 5,869,387 | 02/09/99  | Sato et al.     | 438   | 459                          |
| LA  | AJ  | 6,008,128 | 12/28/99  | Habuka et al.   | 438   | 695                          |
|   | AK  |           |   |                 |   |                              |
|   | AL  |           |   |                 |   |                              |
| <b>FOREIGN PATENT DOCUMENTS</b>   |   |           |   |                 |   |                              |
|   | Document No.  | Date      | Country   | Class           | Sub-class   | Translation (Yes/No)         |
| AM  |   |           |   |                 |   |                              |
| AN  |   |           |   |                 |   |                              |
| AO  |   |           |   |                 |   |                              |
| AP  |   |           |   |                 |   |                              |
| AQ  |   |           |   |                 |   |                              |
| AR  |   |           |   |                 |   |                              |
| <b>OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)</b>   |   |           |   |                 |   |                              |
| AS  | Centura Epi "Epitaxial Deposition Chamber Specifications" Brochure, Applied Materials, March 1994 |           |   |                 |   |                              |
| AT  | EPI CENTURA Systems Specification Brochure, Applied Materials, October 1996                       |           |   |                 |   |                              |
| AU  |   |           |   |                 |   |                              |
| AV  |   |           |   |                 |   |                              |
| AW  |   |           |   |                 |   |                              |
| EXAMINER  | DATE CONSIDERED 2/18/2002   |           |   |                 |   |                              |

EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.